

Special Issue

MOEMS: Micro-Optical MEMS

Message from the Guest Editors

Optical microelectromechanical systems (MEMS), microoptoelectromechanical systems (MOEMS), or optical microsystems are integrated devices or systems that interact with light through actuation or sensing at a micro- or millimeter scale. The multidisciplinary nature of the field has allowed for the collaboration of researchers with a very diverse background and enabled a rapid technological growth that has resulted in enormous commercial success in imaging, laser scanners, and optical communications. In this Special Issue, the current state of this exciting research field will be presented, covering a wide range of topics, including but not limited to:

Guest Editors

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